

U.S. Department of Commerce, Patent and Trademark Office (PTO Form 1449 modified)				Docket No. APPM/8349		Serial No. 10/672,420	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT				Applicant Nguyen, et al.		Confirmation No. Unknown	
(Use several sheets if necessary)				Filing Date September 26, 2003		Group Unknown	
U.S. Patent Documents							
*Examiner Initial		Document Number	Issue Date	Applicant(s) Name	Class	Subclass	Filing Date If Appropriate
✓	A1	6,551,406	04/22/2003	Kilpi	118	728	12/27/2000
✓	A2	6,511,539	01/28/2003	Raaijmakers	117	102	09/08/1999
✓	A3	6,482,733	11/19/2002	Raaijmakers	438	633	04/26/2001
✓	A4	6,482,262	11/19/2002	Elers, Et Al.	117	84	10/13/2000
✓	A5	6,481,945	11/19/2002	Hasper, Et Al.	414	217	04/04/1999
✓	A6	6,478,872	11/12/2002	Chae, Et Al.	117	88	12/20/1999
✓	A7	6,475,910	11/05/2002	Sneh	438	685	09/22/2000
✓	A8	6,475,276	11/05/2002	Elers, Et Al.	117	84	10/13/2000
✓	A9	6,468,924	10/22/2002	Lee, Et Al.	438	763	05/31/2001
✓	A10	6,451,695	09/17/2002	Sneh	438	685	12/22/2000
✓	A11	6,451,119	09/17/2002	Sneh, Et Al.	118	715	11/29/2000
✓	A12	6,447,607	09/10/2002	Soininen, Et Al.	117	200	12/27/2000
✓	A13	6,428,859	08/06/2002	Chiang, Et Al.	427	457	03/19/2001
✓	A14	6,416,822	07/09/2002	Chiang, Et Al.	427	561	03/19/2001
✓	A15	6,416,577	07/09/2002	Suntola, Et Al.	117	88	12/09/1998
✓	A16	6,399,491	06/04/2002	Jeon, Et Al.	438	680	04/06/2001
✓	A17	6,391,785	05/21/2002	Satta, Et Al.	437	704	08/23/2000
✓	A18	6,379,748	04/30/2002	Bhandari, Et Al.	427	255.394	01/17/2000
✓	A19	6,372,598	04/16/2002	Kang, Et Al.	438	399	06/16/1999
✓	A20	6,358,829	03/19/2002	Yoon, Et Al.	438	597	09/16/1999
✓	A21	6,348,376	02/19/2002	Lim, Et Al.	438	253	01/19/2001
✓	A22	6,342,277	01/29/2002	Sherman	427	562	04/14/1999
✓	A23	6,306,216	10/23/2001	Kim, Et Al.	118	725	07/12/2000
✓	A24	6,305,314	10/23/2001	Sneh, Et Al.	118	723	12/17/1999
✓	A25	6,287,965	09/11/2001	Kang, Et Al.	438	648	02/23/2000
✓	A26	6,284,646	09/04/2001	Leem	438	629	08/19/1998
Examiner <u>R</u>				Date Considered <u>9-16-05</u>			
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.							

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U.S. Patent Documents							
*Examiner Initial		Document Number	Issue Date	Applicant(s) Name	Class	Subclass	Filing Date If Appropriate
✓	A27	6,270,572	08/07/2001	Kim, Et Al.	117	93	08/09/1999
✓	A28	6,231,672	05/15/2001	Choi, Et Al.	118	715	05/18/1999
✓	A29	6,207,487	03/27/2001	Kim, Et Al.	438	238	10/12/1999
✓	A30	6,203,613	03/20/2001	Gates, Et Al	117	104	10/19/1999
✓	A31	6,200,893	03/13/2001	Sneh	438	685	03/11/1999
✓	A32	6,197,683	03/06/2001	Kang, Et Al.	438	643	09/18/1998
✓	A33	6,183,563	02/06/2001	Choi, Et Al.	118	715	05/18/1999
✓	A34	6,174,809	01/16/2001	Kang, Et Al.	438	682	12/15/1998
✓	A35	6,174,377	01/16/2001	Doering, Et Al.	118	729	01/04/1999
✓	A36	6,144,060	11/07/2000	Park, Et Al.	257	310	07/31/1998
✓	A37	6,139,700	10/31/2000	Kang, Et Al.	204	192.17	09/30/1998
✓	A38	6,124,158	09/26/2000	Dautartas, Et Al.	438	216	06/08/1999
✓	A39	6,084,302	07/04/2000	Sandhu	257	751	12/26/1995
✓	A40	6,042,652	03/28/2000	Hyun, Et Al.	118	719	09/07/1999
✓	A41	6,015,917	01/18/2000	Bhandari, Et Al.	556	12	01/23/1998
✓	A42	6,015,590	01/18/2000	Suntola, Et Al.	427	255.23	11/28/1995
✓	A43	5,923,056	07/13/1999	Lee, Et Al.	257	192	03/12/1998
✓	A44	5,916,365	06/29/1999	Sherman	117	92	08/16/1996
✓	A45	5,879,459	03/09/1999	Gadigli, Et Al.	118	715	08/29/1997
✓	A46	5,866,795	02/02/1999	Wang, et al.	73	1.36	03/17/1997
✓	A47	5,855,680	01/05/1999	Soininen, Et Al.	118	719	11/28/1995
✓	A48	5,835,677	11/10/1998	Li, Et Al.	392	401	10/03/1996
✓	A49	5,807,792	09/15/1998	Ilg, Et Al.	438	758	12/18/1996
✓	A50	5,796,116	08/18/1998	Nakata, Et Al.	257	66	08/18/1998
✓	A51	5,711,811	01/27/1998	Suntola, Et Al.	118	711	10/02/1996
✓	A52	5,674,786	10/07/1998	Turner, Et Al.	437	225	06/05/1995
Examiner <u>Re</u>					Date Considered <u>9-16-05</u>		
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U.S. Patent Documents							
*Examiner Initial		Document Number	Issue Date	Applicant(s) Name	Class	Subclass	Filing Date If Appropriate
✓	A53	5,503,875	04/02/1996	Imai, Et Al.	427	255.3	03/17/1994
✓	A54	5,483,919	01/16/1996	Yokoyama, Et Al	117	89	08/17/1994
✓	A55	5,480,818	01/02/1996	Matsumoto, Et Al.	437	40	02/09/1993
✓	A56	5,443,647	08/22/1995	Aucoin, Et Al.	118	723	07/11/1994
✓	A57	5,441,703	08/15/1995	Jurgensen	422	129	03/29/1994
✓	A58	5,374,570	12/20/1994	Nasu, Et Al.	437	40	08/19/1993
✓	A59	5,360,738	11/01/1994	Jones, et al.	436	30	04/16/1993
✓	A60	5,294,286	03/15/1994	Nishizawa, Et Al.	156	610	01/12/1993
✓	A61	5,281,274	01/25/1994	Yoder	118	697	02/04/1993
✓	A62	5,225,366	07/06/1993	Yoder	437	108	06/22/1990
✓	A63	4,993,357	02/19/1991	Scholz	118	715	12/21/1989
✓	A64	4,834,831	05/30/1989	Nishizawa, Et Al	156	611	09/04/1987
✓	A65	4,413,022	11/1/1983	Suntola, Et Al.	427	255.2	06/21/1979
✓	A66	4,389,973	06/28/1983	Suntola, Et Al.	118	725	12/11/1981
✓	A67	4,058,430	11/15/1977	Suntola, Et Al.	156	611	11/25/1975
✓	A68	2002/0009544	01/24/2002	McFeely, et al.	427	248.1	08/20/1999
✓	A69	20020082296	06/27/2002	Verschoor, Et Al.	514	557	05/02/2001
✓	A70	20030075925	04/24/2003	Lindfors, Et Al.	285	367	06/28/2002
✓	A71	20030075273	04/24/2003	Kilpela, Et Al.	156	345.33	08/14/2002
✓	A72	20030072975	04/17/2003	Shero, Et Al.	428	704	09/26/2002
✓	A73	20030049942	03/13/2003	Haukka, Et Al.	438	778	08/22/2002
✓	A74	20030042630	03/06/2003	Babcoke, Et Al.	261	121.1	09/05/2001
✓	A75	20030031807	02/13/2003	Elers, Et Al.	427	569	09/17/2002
✓	A76	20030013320	01/16/2003	Kim, Et Al.	438	778	05/31/2001
✓	A77	20030004723	01/02/2003	Chihara	704	260	01/29/2002
✓	A78	20020197402	12/26/2002	Chiang, Et Al.	427	255.39	08/05/2002
Examiner <i>P</i>					Date Considered <i>9-16-05</i>		
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U.S. Patent Documents							
*Examiner Initial		Document Number	Issue Date	Applicant(s) Name	Class	Subclass	Filing Date If Appropriate
✓	A79	20020187256	12/12/2002	Elers, Et Al.	427	99	07/30/2002
✓	A80	20020182320	12/05/2002	Leskela, Et Al.	427	250	03/15/2002
✓	A81	20020177282	11/28/2002	Song	438	300	12/18/2001
✓	A82	20020164423	11/17/2002	Chiang, Et Al.	427	255.28	05/03/2002
✓	A83	20020164421	11/07/2002	Chiang, Et Al.	427	248.1	05/03/2002
✓	A84	20020162506	11/07/2002	Sneh, Et Al.	118	715	06/28/2002
✓	A85	20020155722	10/24/2002	Satta, Et Al.	438	704	04/15/2002
✓	A86	20020146511	10/10/2002	Chiang, Et Al.	427	248.1	10/24/2001
✓	A87	20020144657	10/10/2002	Chiang, Et Al.	118	723 E	10/03/2001
✓	A88	20020144655	10/10/2002	Chiang, Et Al.	118	715	10/24/2001
✓	A89	20020134307	09/26/2002	Choi	118	715	11/30/2000
✓	A90	2002008570	08/15/2002	Lindfors	118	715	04/16/2001
✓	A91	20020106536	08/08/2002	Lee, Et Al.	428	702	02/02/2001
✓	A92	20020104481	08/08/2002	Chiang, Et Al.	118	723	03/19/2001
✓	A93	20020098627	07/25/2002	Pomaredo, Et Al.	438	149	08/31/2001
✓	A94	20020094689	07/18/2002	Park	438	694	03/07/2002
✓	A95	20020092471	07/18/2002	Kang, Et Al.	118	715	01/16/2002
✓	A96	20020086106	07/04/2002	Park, Et Al.	427	248.1	11/07/2001
✓	A97	20020076837	06/20/2002	Hujanen, Et Al.	438	3	11/28/2001
✓	A98	20020076508	06/20/2002	Chiang, Et Al.	427	569	12/19/2001
✓	A99	20020076507	06/20/2002	Chiang, Et Al.	427	569	10/24/2001
✓	A100	20020076481	06/20/2002	Chiang, Et Al.	427	8	10/24/2001
✓	A101	20020073924	06/20/2002	Chiang, Et Al.	118	723 R	10/24/2001
✓	A102	20020068458	06/06/2002	Chiang, Et Al.	438	694	11/26/2001
✓	A103	20020066411	06/06/2002	Chiang, Et Al.	118	724	05/10/2001
✓	A104	20020052097	05/02/2002	Park	438	507	05/03/2001
Examiner <i>Ras</i>					Date Considered <i>9-16-05</i>		
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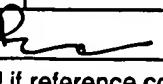
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U.S. Patent Documents							
*Examiner Initial		Document Number	Issue Date	Applicant(s) Name	Class	Subclass	Filing Date If Appropriate
✓	A105	20020048635	04/25/2002	Kim, Et Al.	427	331	10/08/1999
✓	A106	20020041931	04/11/2002	Suntola, Et Al.	427	255.28	05/14/2001
✓	A107	20020031618	03/14/2002	Sherman	427	569	10/09/2001
✓	A108	20020021544	02/21/2002	Cho, Et Al.	361	200	08/07/2001
✓	A109	20020020869	02/21/2002	Park, Et Al.	257	306	12/20/2000
✓	A110	20020007790	01/24/2002	Park	118	715	05/03/2001
✓	A111	20020000598	01/03/2002	Kang, Et Al.	257	301	07/26/2001
✓	A112	20020000196	01/03/2002	Park	118	715	05/03/2001
✓	A113	20010054769	12/27/2001	Raaijmakers, Et Al	257	758	04/26/2001
✓	A114	20010054730	12/27/2001	Kim, Et Al.	257	301	05/23/2001
✓	A115	20010054377	12/27/2001	Lindfors, Et Al.	117	104	04/16/2001
✓	A116	20010042799	11/22/2001	Kim, Et Al.	239	553	02/02/2001
✓	A117	20010042523	11/22/2001	Kesala	122	6.6	05/14/2001
✓	A118	20010041250	11/15/2001	Werkhoven, Et Al.	428	212	03/06/2001
✓	A119	20010034123	10/25/2001	Jeon, Et Al.	438	643	04/06/2001
✓	A120	20010028924	10/11/2001	Sherman	427	255.28	05/24/2001
✓	A121	20010025979	10/04/2001	Kim, Et Al.	257	315	12/04/2000
✓	A122	20010024387	09/27/2001	Raaijmakers, Et Al	365	200	02/22/2001
✓	A123	20010014371	08/16/2001	Kilpi	427	255.28	12/27/2000
✓	A124	20010013312	08/16/2001	Soininen, Et Al.	117	86	12/27/2000
✓	A125	20010011526	08/09/2001	Doering, Et Al.	118	729	01/16/2001
✓	A126	20010009695	07/26/2001	Saanila, Et Al.	427	255.39	01/18/2001
✓	A127	20010009140	07/26/2001	Bondestan, Et Al.	118	725	01/25/2001
✓	A128	20010002280	05/31/2001	Sneh	427	255.28	12/22/2000
✓	A129	20010000866	05/10/2001	Sneh, Et Al.	118	723	11/29/2000
✓	A130						
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U.S. Patent Documents							
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	A131						
	A132						
	A133						
	A134						

Foreign Patent Documents

*Examiner Initial		Document Number	Date	Country	Class	Subclass	Translation	
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✓	B1	WO 02/45167	06/06/2002	WO	H01L	27/00	<input type="checkbox"/>	<input checked="" type="checkbox"/>
✓	B2	WO 02/43115	05/30/2002	WO	H01L		<input type="checkbox"/>	<input checked="" type="checkbox"/>
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							YES	NO
✓	B20	WO 96/17107	06/06/1996	WO	C23C	16/44	<input type="checkbox"/>	<input checked="" type="checkbox"/>
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✓	B22	2001172767 (w/ English Abstract)	06/26/2001	JP	C23C	16/40	<input type="checkbox"/>	<input checked="" type="checkbox"/>
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✓	B25	2000319772 (Abstract Only)	03/28/2000	JP	C23C	16/00	<input type="checkbox"/>	<input checked="" type="checkbox"/>
✓	B26	6224138 (Abstract Only)	05/31/1994	JP	C30B	25/14	<input type="checkbox"/>	<input checked="" type="checkbox"/>
✓	B27	5270997 (Abstract Only)	10/19/1993	JP	C30B	29/68	<input type="checkbox"/>	<input checked="" type="checkbox"/>
✓	B28	5234899 (Abstract Only)	09/10/1993	JP	H01L	21/205	<input type="checkbox"/>	<input checked="" type="checkbox"/>
✓	B29	5206036 (Abstract Only)	08/13/1993	JP	H01L	21/205	<input type="checkbox"/>	<input checked="" type="checkbox"/>
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✓	B33	2 355 727	05/02/2001	GB	C23C	16/44	<input type="checkbox"/>	<input checked="" type="checkbox"/>

OTHER ART

*Examiner Initial		Including Author, Title, Date, Pertinent Pages, Etc.
✓	C1	J.P. Stagg, J. Christer, E. J. Thrush and J. Crawley, "Measurement and Control of Reagent Concentrations in MOCVD Reactor Using Ultrasonics," Journal of Crystal Growth 120(1992) Pages 98-102
✓	C2	"MultiGas™ 2030," MKS Instruments, Inc., Bulletin 2030-04/02
Examiner	<u>P</u>	Date Considered 9-16-05
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Examiner Unknown			
OTHER ART			
*Examiner Initial	Including Author, Title, Date, Pertinent Pages, Etc.		
✓	C3	Kukli, et al., "Tailoring the Dielectric Properties of HfO ₂ -Ta ₂ O ₅ Nanolaminates," Applied Physics Letters, Vol. 68, No. 26, June 24, 1996; p. 3737-9	
✓	C4	Kukli, et al. "Atomic Layer Epitaxy Growth of Tantalum Oxide Thin Films from Ta(OC ₂ H ₅) ₅ and H ₂ O," Journal of the Electrochemical Society, Vol. 142, No. 5, May 1995; p. 1670-5	
✓	C5	Kukli, et al., "In situ Study of Atomic Layer Epitaxy Growth of Tantalum Oxide Thin Films From Ta(OC ₂ H ₅) ₅ and H ₂ O," Applied Surface Science, Vol. 112, March 1997, p. 236-42	
✓	C6	Kukli, et al., "Properties of Ta ₂ O ₅ -Based Dielectric Nanolaminates Deposited by Atomic Layer Epitaxy," Journal of the Electrochemical Society, Vol. 144, No. 1, Jan. 1997; p. 300-6	
✓	C7	Kukli, et al., "Properties of {Nb _{1-x} Ta _x } ₂ O ₅ Solid Solutions and {Nb _{1-x} Ta _x } ₂ O ₅ -ZrO ₂ Nanolaminates Grown by Atomic Layer Epitaxy," 1997; p. 785-93	
✓	C8	Ritala, M., et al., "Chemical Vapor Deposition," January 1999, p. 6-9	
✓	C9	Rossnagel, et al. "Plasma-enhanced Atomic Layer Deposition of Ta and Ti for Interconnect Diffusion Barriers," J. Vac. Sci. Technol. B., Vol. 18, No. 4 (July 2000); p2016-20	
✓	C10	Niinisto, et al. "Synthesis of Oxide Thin Films and Overlays by Atomic Layer Epitaxy for Advanced Applications," Materials Science and Engineering B41 (1996) 23-29	
✓	C11	Eisenbraum, et al. "Atomic Layer Deposition (ALD) of Tantalum-based materials for zero thickness copper barrier applications," Proceedings of the IEEE 2001 International Interconnect Technology Conference (Cat. No. 01EX461) 2001	
✓	C12	Clark-Phelps, et al. "Engineered Tantalum Aluminate and Hafnium Aluminate ALD Films for Ultrathin Dielectric Films with Improved Electrical and Thermal Properties," Mat. Res. Soc. Symp. Proc. Vol. 670 (2001)	
C13			
C14			
C15			
Examiner <u>Ra</u>		Date Considered <u>9-16-05</u>	
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.			